



Evactron®

By XEI Scientific

Evactron® E16 Plasma De-Contaminators

Vacuum Chamber Cleaning System for Small Volumes

The Evactron E16 De-Contaminators are compact yet simplified plasma cleaners for Electron and Ion Beam Instrument load locks such as SEMs, TEMs, FIBs, and sample preparation chambers. The E16 delivers gentle and effective cleaning for superior resolution and imaging plus improved detector and probe sensitivity that are compromised by contamination.

New design features of the Evactron E16 Plasma Radical Source (PRS) include a unique flush-mounting flange and compact size to fit in restricted spaces on a chamber wall. The Evactron E16 Power Centre controller has a small footprint and can be placed horizontally or vertically to conserve space.

System Features:

- RF Power: 5 to 16W continuous
- Dual action cleaning using plasma and UV afterglow
- Energy efficient radio frequency hollow cathode plasma (RFHC)
- Compact PRS—WxHxD: 2.5"x2.125"x3.75" (6.3x5.4x9.5cm)
- "Pop" ignition at operating vacuum
- Programmable ignition power, cleaning power, cycle time, number of cycles
- Power Centre controller—WxHxD: 12.25"x3.5"x9.34" (31x8.9x23.7cm)
- Touchpad programming of cleaning recipes
- Wide range of pressure operation: 1Torr to 1.0 E-3 Torr
- Ignition can start at pressures down to 1.0 E-8 Torr
- Fixed input air flow rate, no adjustments needed
- Turbo pump compatible
- Non-damaging to sensitive components
- PRS can be flush-mounted on the chamber or a KF40 adapter is available
- No match or gas flow adjustments needed for plasma ignition
- TUV, NRTL and CE approval pending



Evactron® E16 Plasma Cleaner including PRS, Power Centre Controller and E-TC Touchpad

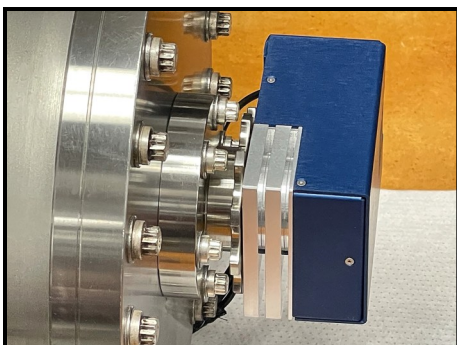
Remote Plasma Cleaner

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Evactron E16 Products



Evactron E16 PRS Flush-mount

The **Evactron E16 Plasma De-Contaminator** was designed to remove hydrocarbon contamination from high vacuum chambers such as SEMs and FIBs. Its compact design fits most models of SEM and FIB chambers and loadlocks. It utilizes air plasma and UV afterglow to rapidly reduce hydrocarbon contamination.

Evactron E16 System Specifications:

- Compact E16 plasma radical source (PRS)
- Power Centre controller and touchpad operation
- PRS Dimensions: W 2.5" X D 3.75" X H 2.125"
- Chassis dimensions: W 12.25" X D 9.34" X H 3.5"
- RF Power: 5 - 16 Watts at 13.56 MHz RFHC
- 100-240 VAC 50/60 Hz input
- RoHS Compliant



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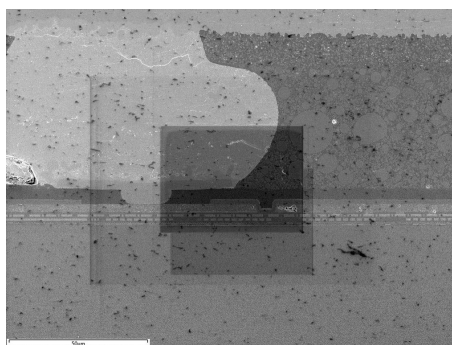
Contact: sales@evactron.com



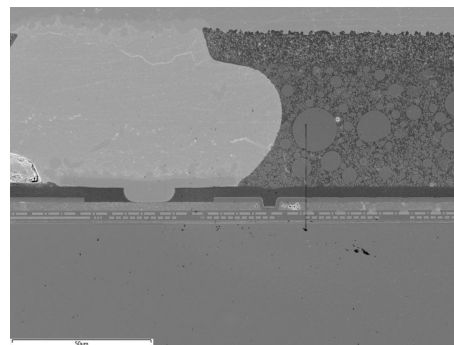
Evactron E16 air plasma and horizontal Power Centre



Evactron E16 PRS, touchpad and vertical Power Centre



Before Evactron Cleaning



After Evactron Cleaning

